

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application

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Title: Apparatus and Method for Reactive Atom
Plasma Processing for Material Disposition

PATENT APPLICATION

Art Unit: 1765

Examiner: Lan Vinh

Customer No. 23910

**INFORMATION DISCLOSURE STATEMENT AFTER NOTICE OF ALLOWANCE
PURSUANT TO 37 C.F.R. §1.97(i)**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicant is filing this Information Disclosure Statement (IDS), after receipt of the Notice of Allowance mailed August 6, 2007, for the above-captioned application. The patents/patent publication documents and non-patent documents listed in the IDS were recently cited by the Office in other patent applications for the same client.

This filing is not intended to represent that the references cited herein are material to patentability as defined in 37 C.F.R. §1.56. Rather, Applicant does not believe that they affect the patentability of the allowed claims in the above-captioned application. Applicant offers that the references are being submitted to satisfy the duty of disclosure.

	U.S. Patent References		
	Patent Number	Issue Date	First Named Inventor
	3,264,508	Aug. 2, 1966	Lai, et al.
	3,830,428	Aug. 20, 1974	Dyos
	3,937,866	Feb. 10, 1976	Sunnen, et al.
	3,953,704	Apr. 27, 1976	Bejat, et al.
	4,035,604	Jul. 12, 1997	Meleke, et al.
	4,339,326	Jul. 13, 1982	Hirose, M.

U.S. Patent References		
Patent Number	Issue Date	First Named Inventor
4,439,463	Mar. 27, 1984	Miller
4,440,556	Apr. 3, 1984	Oh, et al.
4,440,558	Apr. 3, 1984	Nath, et al.
4,668,366	May 26, 1987	Zarowin, C.
4,689,467	Aug. 25, 1987	Inoue, K.
4,863,501	Sep. 5, 1989	Mansfield
4,897,282	Jan. 30, 1990	Kniseley, et al.
4,908,492	Mar. 13, 1990	Okamoto, Y., et al.
4,924,061	May 8, 1990	Labat, J., et al.
4,958,767	Sep. 25, 1990	Labrot, M., et al.
5,095,189	Mar. 10, 1992	Frind, et al.
5,144,151	Sep. 1, 1992	Thorne, B., et al.
5,206,471	Apr. 27, 1993	Smith, Donald K.
5,298,714	Mar. 29, 1994	Szente, et al.
5,321,224	Jun. 14, 1994	Kamimura, et al.
5,349,154	Sep. 20, 1994	Harker, A., et al.
5,356,674	Oct. 18, 1994	Henne, et al.
5,364,434	Nov. 15, 1994	Saghera, et al.
5,429,730	Jul. 4, 1995	Nakamura, et al.
5,474,642	Dec. 12, 1995	Zorina, et al.
5,503,677	Apr. 2, 1996	Morsen, et al.
5,639,699	Jun. 17, 1997	Nakamura, et al.
5,680,382	Oct. 21, 1997	Inoue, M.
5,820,940	Oct. 13, 1998	Gorynin, et al.
5,916,455	Jun. 29, 1999	Kumagai
5,925,266	Jul. 20, 1999	Gange, Peter H.
5,932,293	Aug. 3, 1999	Belaschenko, et al.
5,998,757	Dec. 7, 1999	Schneider
6,159,388	Dec. 12, 2000	Yanagisawa, et al.
6,221,268	Apr. 24, 2001	Li, K., et al.
6,229,111	May 8, 2001	McCay, et al.
6,262,523	Jul. 17, 2001	Selwyn, et al.
6,284,668	Sep. 9, 2001	Imashashi
6,312,554	Nov. 6, 2001	Ye, Yan
6,388,225	May 14, 2002	Blum, et al.
6,406,590	Jun. 18, 2002	Ebata, et al.
6,417,028	Jul. 9, 2002	Wensel, R.W.
6,424,091	Jul. 23, 2002	Sawada, et al.
6,482,476	Nov. 19, 2002	Liu, S. F.
6,491,978	Dec. 10, 2002	Kalyanam, J.
6,551,860	Apr. 22, 2003	Uner, Jason, et al.
6,683,272	Jan. 27, 2004	Hammer, et al.
6,821,500	Nov. 23, 2004	Fincke, et al.

	U.S. Patent Publications		
	Publication Number	Publication Date	Applicant
	2001/0052257	Dec. 20, 2001	Margerle, Robt.
	2002/0058143	May 16, 2002	Hunt, Andrew T., et al.
	2002/0100751	Aug. 1, 2002	Carr, Jeffrey W.
	2002/0177003	Nov. 28, 2002	Myrick, James J.
	2003/0113479	Jun. 19, 2003	Fukuda, K., et al.
	2003/0230112	Dec. 18, 2003	Ikeda, H., et al.
	2004/0115936	Jun. 17, 2004	DePetrillo, Al, et al.
	2004/0118348	Jun. 24, 2004	Mills, Randell L.
	2005/0018199	Jan. 27, 2005	LeBlanc, Philip
	Foreign Patent References		
	Document Number	Publication Date	Country
	EP 0 284 436 A2	Sep. 28, 1988	EP
	JP 50-153024	Dec. 9, 1975	JP
	JP 63-289798	Nov. 28, 1988	JP
	JP 01-96040 A	Apr. 14, 1989	JP
	JP 05-135896 A	Jun. 1, 1993	JP
	JP 09-069397	Mar. 11, 1997	JP
	JP 09-115865	May 2, 1997	JP
	JP 10-298318 A	Nov. 10, 1998	JP
	JP 2000-173994A	Jun. 23, 2000	JP
	JP 2000-174004A	Jun. 23, 2000	JP
	JP 2000-183044 A	Jun. 30, 2000	JP
	JP 2002-170815	Jun. 14, 2002	JP
	WO 97/045856A1	Dec. 4, 1997	PCT
	WO 02/06211 A2	Aug. 8, 2002	PCT
	Non Patent References		
	Bollinger, et al., Rapid, Non-Contact Optical Figuring of Aspheric Surfaces with Plasma Assisted Chemical Etching (PACE), 1990, SPIE Vol. 1333, Advanced Optical Manufacturing and Testing, pp. 44-57.		
	Kulikovsky, Andrei A., Production of Chemically Active Species in the Air by a Single Positive Streamer in a Nonuniform Field, IEEE Transactions on Plasma Science, vol. 25, pp 439-446, June 1997.		
	Takino et al., Computer Numerically Controlled Plasma Chemical Vaporization Machining with a Pipe Electrode for Optical Fabrication, Applied Optics, Vol. 37, No. 22, pp. 5198-5210, August 1, 1998.		

Applicant respectfully requests that this IDS and these references be placed in the application file.

No fee is believed due in connection with this paper. However, the Commissioner is authorized to charge any underpayment or credit any overpayment to Deposit Account No. 06-1325 for any matter in connection with this filing, including any fee for extension of time, which may be required.

Respectfully submitted,

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